

Amendments to the Specification

Please replace paragraph [0001] with the following amended paragraph:

[0001] This application is related to the subject matter of commonly owned, co-pending application Serial Number 10/677,524, filed on even date herewith, the specification of which is incorporated herein by reference.

After paragraph [0032] please insert new paragraph [0032a]:

[0032a] Figure 4 is a sectional view through an alternate embodiment of a test apparatus according to the invention.

Please replace paragraph [0036] with the following amended paragraph:

[0036] Four first, mushroom-shaped holding rods 10 are secured to the chuck 1 in such a way that they can execute small vertical movements and engage into second, groove-like holding members 11 on the substrate carrier 12. The groove-like holding members 11 enable the substrate carrier to be inserted through an opening 4 of the vacuum chamber with the substrate and possibly the ~~probe holders 24~~ probe holders 19 attached thereto. Rods 10 are fixed to the chuck drive 2 via a holding pin 13 made from polymer fiber material and are held in a lower position by springs 14. As a result of the heads 15 of the first holding rods 10 engaging into the second holding member 11, the first holding rods 10 are pulled by the second holding members 11 out of their lower position into an upper position, in which they are held by ~~by~~ the second holding member 11, so that the force of the springs 14 produces a defined clamping action onto the substrate carrier 12 and good thermal contact is produced between the receiving surface 16 of the chuck 1 and the underside of the substrate carrier 12 and test substrate 17 held by the substrate carrier 12.

Please replace paragraph [0038] with the following amended paragraph:

[0038] The temperature required to test the test substrate 17 is controlled both at the chuck 1 and at the thermal radiation shield 18 by means of a measuring and control unit. The probe holder 19 forms the middle part of the thermal radiation shield and consists of heat-storing material of very good thermal conductivity. A circular through-opening 23 is arranged in the

center, accurately beneath the inspection opening in the vacuum chamber. This through-opening 23 is closed off by a glass transparent closure 30, such as a glass, which reflects infrared radiation.

After paragraph 0039, please insert the following new paragraph [0039a]:

[0039a] Figure 4 illustrates a further alternate embodiment of the invention, in which the chuck comprises a chuck body 1 with a chuck surface 16 and a chuck plate 28 which rests on the chuck surface 16 over its entire area and can be released from the chuck body. Thus, the releasable chuck plate 28 can be removed from the vacuum chamber in order for the test substrate to be mounted on the chuck. The chuck plate 28 can be connected to the chuck body 1 in the same way as that described above, via the thermally decoupling holding pins and heads. In such an arrangement, the corresponding holding means would be located on the chuck plate 28 rather than the test substrate 12.